

Notice of References Cited	Application/Control No. 09/890,864	Applicant(s)/Patent Under Reexamination HAUSSLER ET AL.	
	Examiner Brian L. Mutschler	Art Unit 1753	Page 1 of 1

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	B	US-5,220,181	06-1993	Kanai et al.	257/40
	C	US-			
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	M	US-			

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NON-PATENT DOCUMENTS

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	U	Schaffer et al., The Science and Design of Engineering Materials (1995) pp. 40-41.
	V	Tjhen et al., "Properties of Piezoelectric Thin Films for Micromechanical Devices and Systems," MEMS 1991 Proceedings, IEEE, (1991) pp. 114-119.
	W	Kirk-Othmer Encyclopedia of Chemical Technology, Physical properties of zinc oxide and pure copper.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.